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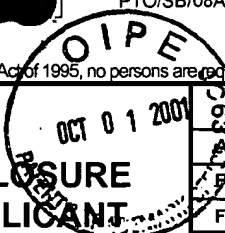
INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet 1 of 2

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Application Number 09/826,583
Filing Date 04/06/01
First Named Inventor Marc A. Unger
Group Art Unit 1772
Examiner Name Unassigned
Attorney Docket Number 20174-003010US



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U.S. PATENT DOCUMENTS

Examiner Initials *	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
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Examiner Initials*	Cite No. ¹	Foreign Patent Document			Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Office ³	Number ⁴	Kind Code ⁵ (if known)			
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}	22	EP	999 055	A2		10-05-2000	
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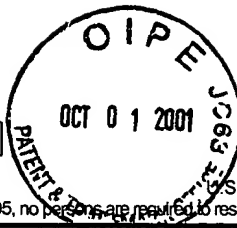
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Attorney Docket Number	20174-003010US

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OTHER PRIOR ART -- NON PATENT LITERATURE DOCUMENTS

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